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Ootake et al.

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(54) **SCREEN PRINTER, COMPONENT MOUNTING LINE, AND SCREEN PRINTING METHOD**

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(71) Applicant: **PANASONIC INTELLECTUAL PROPERTY MANAGEMENT CO., LTD.**, Osaka (JP)

(58) **Field of Classification Search**
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(72) Inventors: **Yuuji Ootake**, Yamanashi (JP); **Mitsuru Kouchi**, Yamanashi (JP); **Seiya Kuroda**, Yamanashi (JP)

(73) Assignee: **PANASONIC INTELLECTUAL PROPERTY MANAGEMENT CO., LTD.**, Osaka (JP)

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(*) Notice: Subject to any disclaimer, the term of this patent is extended or adjusted under 35 U.S.C. 154(b) by 0 days.

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Primary Examiner — Leslie J Evanisko

(74) *Attorney, Agent, or Firm* — Pearne & Gordon LLP

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(57) **ABSTRACT**

A screen printer includes a mask, a substrate holding unit that clamps and holds a substrate below the mask by clamping members, a substrate holding unit moving mechanism that moves the substrate holding unit to contact the substrate with a lower surface of the mask, a paste filling unit that fills pattern holes of the mask with a paste, mask suction portions provided in the clamping members which suck the mask contacted with the substrate. The mask suction portions keep sucking the mask when the substrate holding unit moving mechanism moves the substrate in a direction away from the mask to perform plate releasing, and release the suction of the mask in a state in which the mask sucked to the mask suction portions maintains a posture parallel to the substrate after the movement of the substrate is started.

4 Claims, 11 Drawing Sheets

